

Docket No.: 50395-124



**PATENT**

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re Application of

Makoto KATAYAMA, et al.

Serial No.: 09/993,410

Filed: November 21, 2001

For: OPTICAL DEVICE

Group Art Unit: 2882

Examiner: Caley, Michael

TECHNICAL  
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MAY 17 2003  
2300

**SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

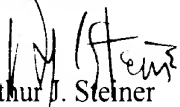
Applicants submit herewith an English language translation of the publication entitled "Silicon Micromachining High Technology" Science Forum, March 1992, which was submitted in the Information Disclosure Statement filed on January 17, 2002. Applicants note that the Examiner included a copy of the Form PTO-1449 and indicated consideration of the "Silicon Micromachining High Technology" publication by providing the Examiner's initials adjacent the listing of that reference. In order to ensure that the Examiner has a complete understanding of this reference, an English language translation is submitted herewith.

Since the original Information Disclosure Statement was filed on January 17, 2002, within three months of the U.S. filing date or before the mailing of a first Office Action on the merits, it is not believed that any certification or fee is required.

Please charge any shortage in fees due in connection with the filing of this paper, including extension of time fees, to Deposit Account 500417 and please credit any excess fees to such deposit account.

Respectfully submitted,

MCDERMOTT, WILL & EMERY

  
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**Date: May 6, 2003**